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17621 U.S. PTO

Docket No. 008226/DSM/BCVD/JW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Mail Stop Patent Application
 Commissioner for Patents
 P.O. Box 1450
 Alexandria, Virginia 22313-1450

Re: Inventor(s): Zhenjiang Cui, Jun Zhao, Rick J. Roberts, Shulin Wang, Errol A. C. Sanchez, and Aihua Chen
 Title: Electron Beam Treatment of Si₃N₄ Films

Transmitted herewith is the patent application identified above, including:

- ☒ Specification, claims and abstract, totaling 18 pages.
☒ Drawings totaling 2 pages, Formal ☒ Informal.
☒ Executed Declaration and Power of Attorney.
☒ Assignment of the invention to Applied Materials, Inc.
☒ Assignment Recordation Cover Sheet
☒ Information Disclosure Statement

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FEE CALCULATION

Fee Items	Claims Filed	Included With Basic Fee	Extra Claims	Fee Rate	Total
Total Claims	9	- 20 =		X \$ 18.00	\$ 000.00
Independent Claims	2	- 3 =		X \$ 86.00	\$ 000.00
Basic Filing Fee				\$770.00	\$ 770.00
TOTAL FEES					\$ 770.00

☒ The Commissioner is hereby authorized to charge \$ 770.00 to Deposit Account No. 50-1074.

☒ The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. 50-1074. A duplicate copy of this transmittal is enclosed.

☒ Please address all future correspondence to:
PATENT COUNSEL, MS/2061
APPLIED MATERIALS, INC.
Legal Affairs Department
P.O.BOX 450A
Santa Clara, CA. 95052

I hereby certify that this correspondence is being deposited with the United States Postal Service as express mail in an envelope addressed to: Box Patent Application, Assistant Commissioner for Patents, Washington, D.C. 20231.

Express Mail Receipt No. E V 3 4 1 1 0 9 4 7 3 U S

Date of Deposit APR. 13 2004

Signature [Signature]

Respectfully submitted,

[Signature]
 Robert W. Mulcahy
 Registration No. 25,436